



Att. Docket No. 10191/1690

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Appl. Serial No. : 09/762,985 Confirmation No. 2674
Title : DEVICE AND METHOD FOR
ETCHING A SUBSTRATE USING
AN INDUCTIVELY COUPLED PLASMA
Applicant(s) : Volker BECKER et al.
Filed : May 8, 2001
TC/A.U. : 1763
Examiner : Luz L. Alejandro Mulero
Docket No. : 10191/1690
Customer No. : 26646

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

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6/28/2004

AARON C. DEDITCH
(33,865)

AMENDMENT

S I R:

In response to the Office Action mailed on March 3, 2004 (the three-month response date for which has been extended by one month from June 3, 2004 to July 3, 2004 by the accompanying Transmittal and Petition to Extend), please reconsider the above-identified application based on the following:

Amendments to the Claims are reflected in the listing of the claims which begins on page 2 of this paper.

Remarks begin on page 9 of this paper.